

# HV/HR CMOS in Oxford: Facilities, experience, and interests

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# Oxford Particle Physics Microstructure Detector Laboratory - OPMD

Currently Under construction – expected completion in Oct 2015

Focused on generic R&D and ITK Strip/Pixel Module production

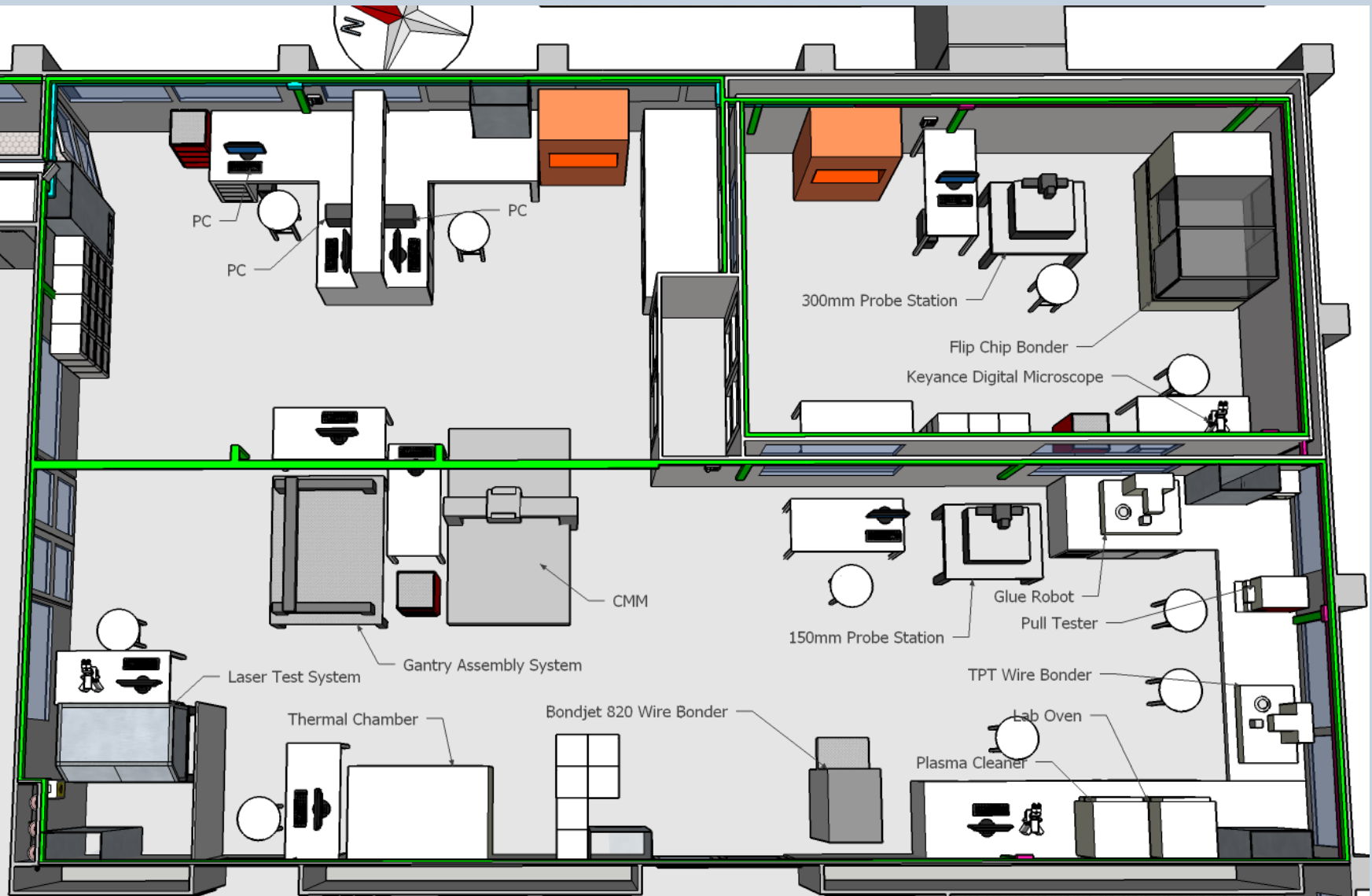
## **Clean Rooms**

- 160 m<sup>2</sup> of class 10,000 clean room
- 35 m<sup>2</sup> of class 100 clean room
- Vacuum, Dry Compressed Air, Nitrogen & DI water as piped services

## **Equipment**

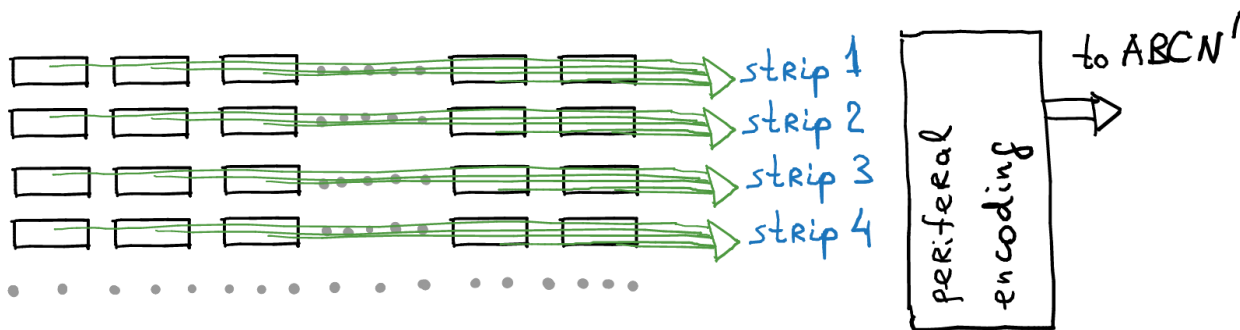
- Semiprobe 300mm probe station with thermal chuck (delivery this month)
- Hesse Bondjet 820 automatic wire bonder (delivery expected Oct/Nov)
- Dage 4000Plus pull tester (Oct/Nov)
- OGP CNC500 Smartscope optical metrology system (Oct/Nov)
- Keyence VHX500 digital inspection microscope (Oct/Nov)
- Weiss Thermal chamber WTL100 (+50°C → -50°C) (Oct/Nov)
- Henniker Bench top Plasma Cleaner (Oct/Nov)
- Aerotech pick and place assembly gantry (Sept/Oct)
- Nordson EFD Glue Robot (Delivered this week)

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# CMOS replacement of sensors

- Participating in the evaluation of HV-HR CMOS as a sensor replacement
- Our activities up to now focused on the evaluation of strip
  - Amplifiers and comparators could be on sensor but the rest of digital processing, command I/O, trigger pipelines, etc will go into a readout ASIC
  - Transmit high-speed information instead of individual analog signals to readout ASICs.
  - The active area is *pixelated*, with connections to the periphery that can yield 2D coordinates
  - Looking at  $\sim 40 \mu\text{m}$  pitch and  $800 \mu\text{m}$  length of pixel
  - Max reticle sizes are  $\sim 2 \times 2 \text{ cm}^2$ . Therefore rows of 4-5 chips could be the basic units (yield performance is critical here).
  - R&D with two foundries AMS and TJ - Pixel efforts have more, e.g. L-foundry

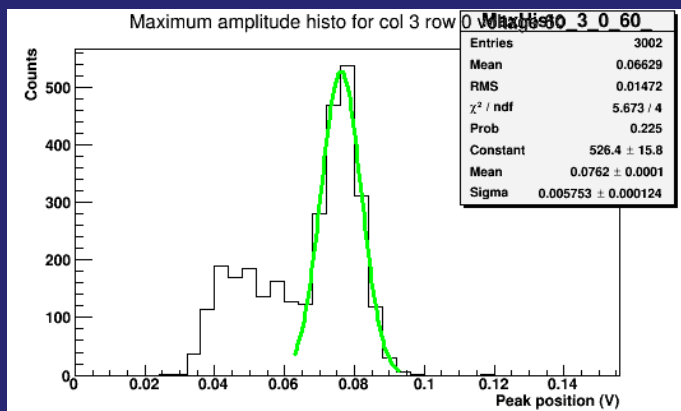


- Cost savings.
- Faster construction
- Less material in the tracker.

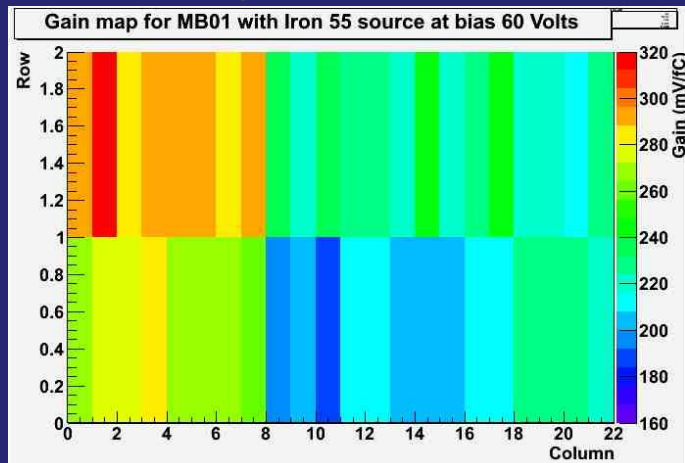
# HVStrip 1 – Ivan Peric (Karlsruhe/KIT)

- AMS35 Technology
- 22x2 pixels, 40x400  $\mu\text{m}^2$  each, 750  $\mu\text{m}$  total thickness

## Fe<sup>55</sup> Calibration



Single spectrum

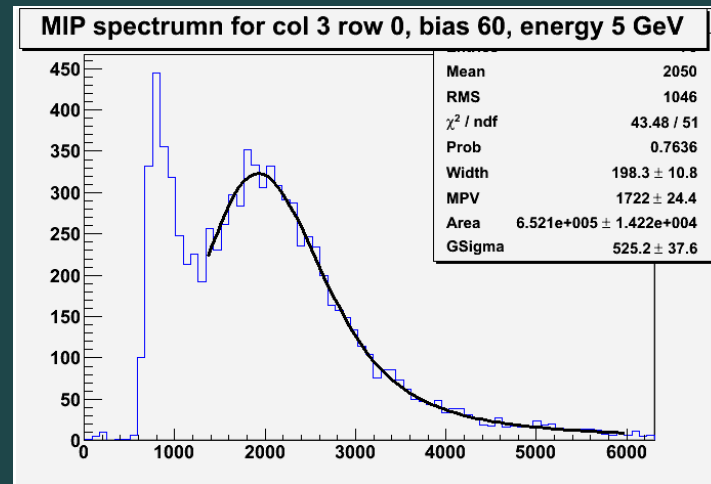


Gain map

HV-CMOS Infrastructure

Two regions:  
linear transistor  
(left) and  
enclosed  
transistor  
(right)

Test beam at DESY  
With 3, 4, and 5 GeV  
Electrons at different

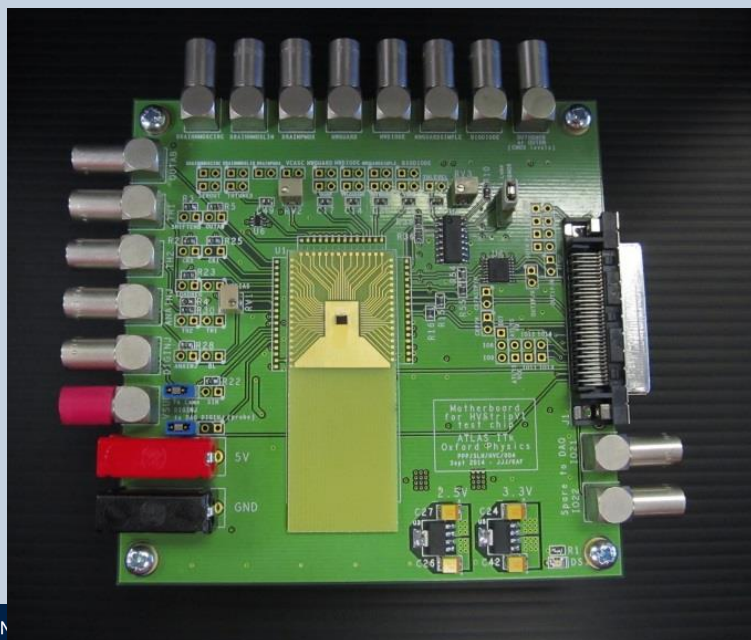


Telescope integration could lead to  
better understanding of the performance  
including charge sharing

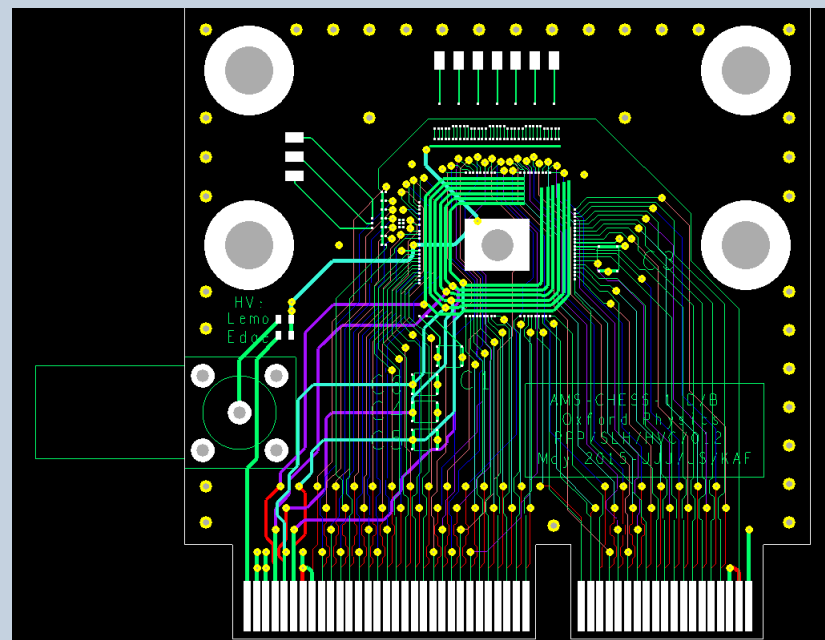
# Hardware development

- Developed electronics for testing HVStripV1 chip on behalf of Strip CMOS collaboration
- Motherboard (green) for readout electronics and connectors
- Daughterboard (yellow) for low-activation chip fanout, to favour irradiation

- Currently developing hardware for testing HV and HR “CHESS” Strip CMOS detectors
- HV-CHESS-1 daughterboard being manufactured this week
- 79 output channels of varied active pixels and amplifiers



HV-CMOS Infrastructure

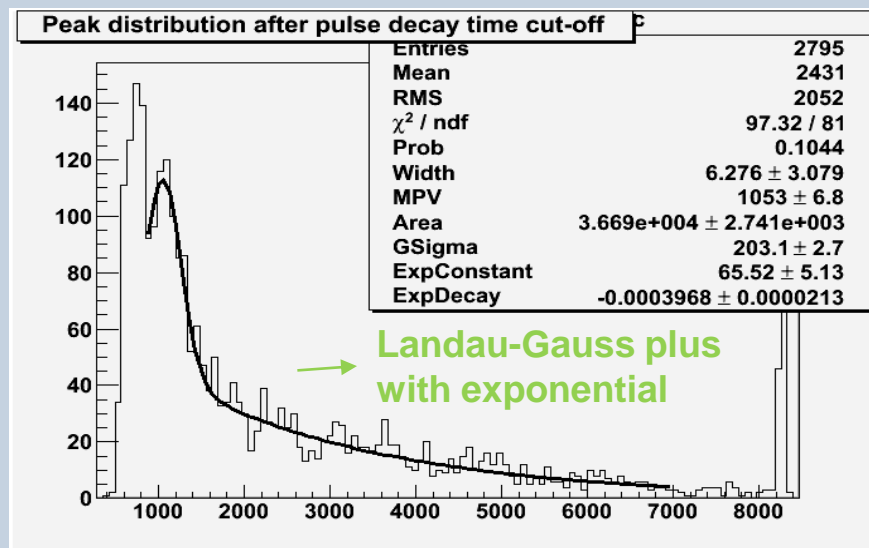
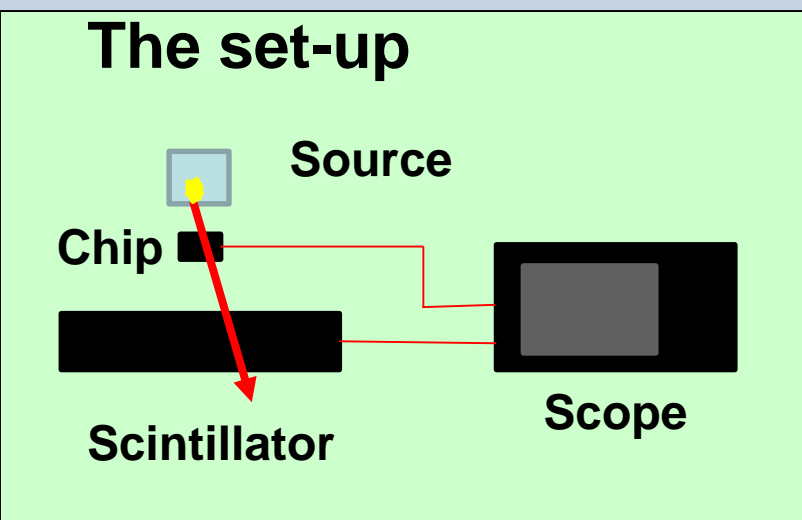


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# Proton irradiation

- Samples irradiated with 27 MeV protons at Birmingham
- Irradiation divided in 4 steps of 15 minutes
- Total irradiation of  $8.8 \times 10^{14}$  and  $7.6 \times 10^{14}$   $n_{eq}/cm^2$  respectively
- After annealing ( $60^\circ$  for 80 minutes)  $Sr^{90}$  spectrum could be observed (measurements done at Cambridge)



- Exponential function to parameterize the observed background
- MIP peak observed, lower MPV than unirradiated (~60%)

# Interests and Possible Contributions

- We are especially interested in:
  - Task 6.3 Sensor development:
    - Characterise test-structures and sensors using electrical measurements, lasers, sources and test beams
    - Perform irradiation campaigns to validate the radiation hardness of each process technology and sensor design
  - Task 6.4 Hybridisation
    - Perform basic R&D on capacitive interconnection
    - Setup production facilities for full-prototype assemblies (chips on test boards)
    - Deliver full assemblies to all participating projects
    - Investigate options for future industrialisation of the interconnection process